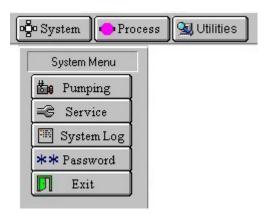
ALD OPERATION

Procedure:

Log on to the system by clicking on the **System** button at the top of the screen and select ****Password** from the drop down menu.

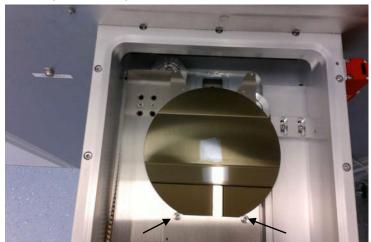
username: OPT password: OPT

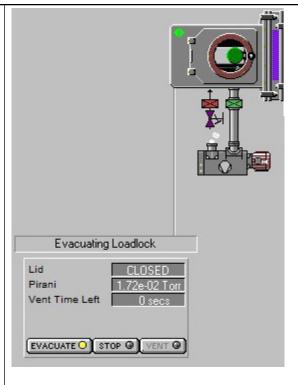


On the load lock image Press STOP and then VENT. When the loadlock reaches atmosphere and the Vent Time Left is 0 secs, open the loadlock lid and place your samples on the 6" Si wafer carrier in the loadlock.

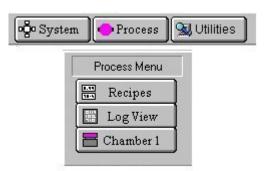
Verify that the 6" Si wafer carrier flat is right against two screw stops (adjust as needed) shown below. Close the lid and pump the load lock down by pressing **STOP** and then **EVACUATE**.

When the Green dot on the loadlock appears, it indicate it is ready to run the process.

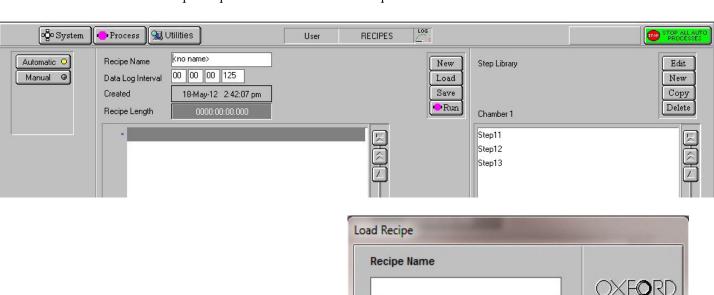




To process a wafer, click on the **Process** button and select **Recipes** from the drop down menu:

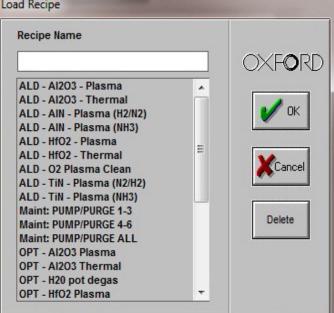


Click on the **Load** button to pull up the list of available recipes.

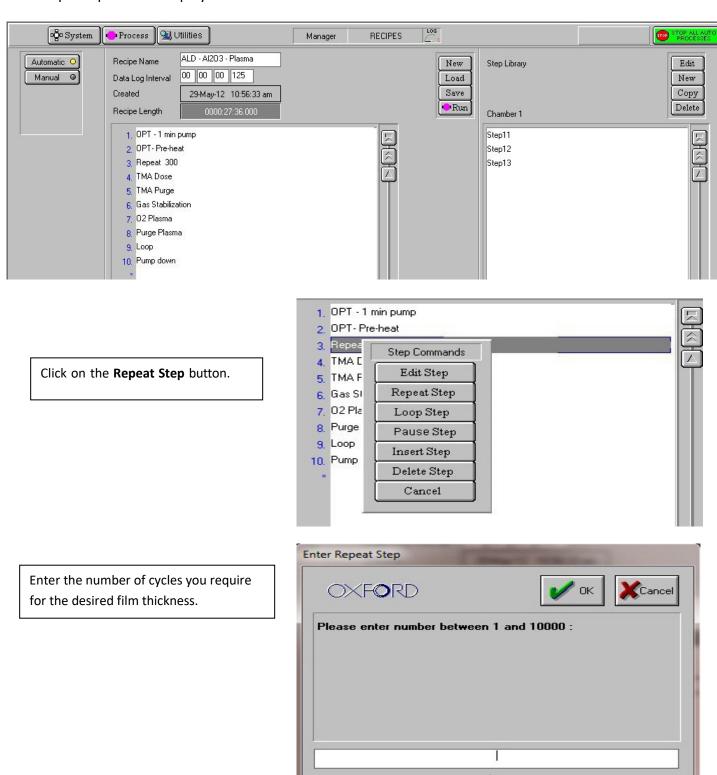


Click on the desired recipe and click **OK**.

Click "Yes" to overwrite previously loaded recipe.

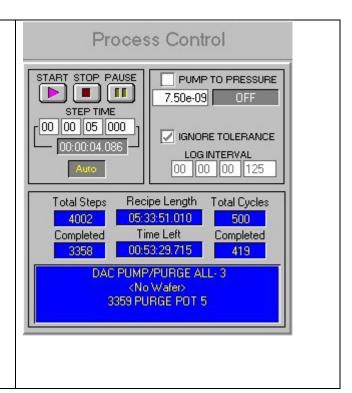


The recipe steps will be displayed on the screen.

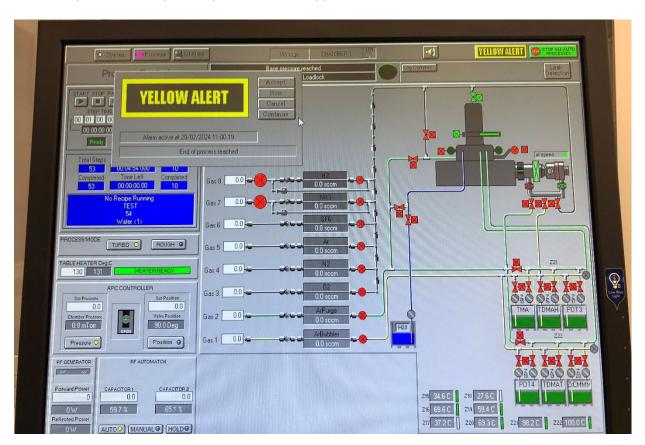


Click on the **Run** button to begin processing the wafer.

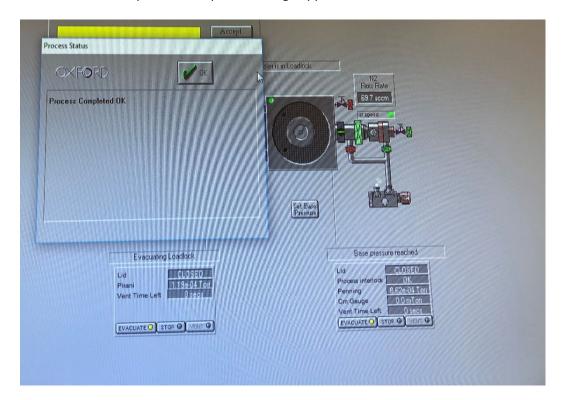
The process progress may be monitored from the main chamber screen, and the time to completion is detailed in the Process Control section.



When the process is complete, a yellow alert will appear, DO NOT ACKNOWLEDGE IT:



Wait until the process complete message appears:



Click OK, the wafer will be returned to the loadlock automatically for removal.

To unload a wafer from the loadlock, click on the **Pumping** button from the **System** menu.

Press **STOP** and then **VENT**. The Vent Time Left feedback will start counting down. When the loadlock reaches atmosphere, open the loadlock lid and remove your wafer on the load arm.

Close the lid and pump the load lock down by pressing **STOP** and then **EVACUATE**.